

<b>FORM PTO-1449</b> <b>INFORMATION DISCLOSURE STATEMENT</b>				<b>Atty Docket</b> <b>TAI 145</b>		<b>Application No.</b> <b>To Be Assigned</b>	
				<b>Applicant</b> <b>Toyokazu Sakata</b>			
				<b>Filing Date</b> <b>November 26, 2003</b>		<b>Group Unit</b> <b>To Be Assigned</b>	
U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Sub-Class	Filing Date
LV	AA	6,355,572	03/12/02	Ikegami			
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Sub-Class	Translation
LV	AK	7-94483	04/07/95	Japan			Abstract
LV	AL	2001-77086	03/23/01	Japan			Abstract
	AM						
	AN						
OTHER (Including Author, Title, Date, Pertinent Pages, etc.)							
LV	AO	"Dry Etching of Organic Low Dielectric Constant Film without Etch Stop Layer" M.Mizumura et al. JJAP, Vol. 41, pp. 425-427 (no date)					
LV	AP	"Highly Selective Etching of Organic SOG to SiN for Cu Damascene Interconnects Using New Gas Chemistry of C <sub>2</sub> F <sub>4</sub> /N <sub>2</sub> /Ar" S. Uno et al. Proc. Of Dry Process Symp., pp. 215-220(1999)					
	AQ						
Examiner <u>LAN VINH</u>				Date Considered <u>7/18/05</u>			
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.							